

DCVD PROCESS: CONCEPTS & MEASUREMENTS

Who should attend?

This course is designed for those individuals in the semiconductor industry who require the knowledge and skills for DCVD Process: Concepts and Measurements.

Course Benefits

Increase knowledge of:
Process fundamentals,
Integration of process in wafer fabrication,
Process measurement techniques,
Post-PM process recovery.

Course Objectives

- Provide a general understanding of the TEOS and Silane Plasma Enhanced CVD Processes and the SACVD process.

Course Modules

1. *Introduction*
2. *Safety*
3. *Overview*
4. *Plasma Fundamentals*
5. *DCVD Chemistry*
6. *DCVD Process*
7. *Measurement*

Registration Information

Prerequisites:

- *It is required that the student be familiar with the system hardware and the basic system components / operations through completion of the hardware/software courses and/or other hands on experience with the Precision 5000 and Centura DCVD system.*

Course Length: 6 Hours

Course Type: Web-based Training

Course Number: TRNWEB-13

To enroll or for more information on our products and services, please call our registrar at one of the numbers below or go to www.appliedtraining.com.

- 1-800-468-8888, option 4 (United States)
- 1-512-272-0027 (International)

Computer System Requirements:

Attending this course requires a Windows 98, NT, 2000 or XP computer using Internet Explorer 5.5 or higher. 128MB RAM or higher and high-speed Internet access is also highly recommended.